

AMENDMENTS TO THE ABSTRACT

Please insert the following Abstract after the claims:

ABSTRACT

There are provided herein a method and an apparatus for deposition of films of coating materials on a substrate, of particular use in obtaining superconductive composite tapes for deposition of films of superconductive oxides and/or buffer layers. A step of deposition of the film on the substrate is associated to a step of gas treatment in situ, in which a flow of gas is sent towards a working surface of the substrate or of the film growing on the substrate. The gas-treatment step is performed via ultrasound-expansion nozzles.